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Application No.: 10/603,924

APR - 4 2006 ·

Docket No.: JCLA7109

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner: NGUYEN, THANH T

Group Art Unit: 2813

In re PATENT APPLICATION of

Applicants: Shao-Chung Hu

Serial No.: 10/603,924

Filed : June 24, 2003

For : POST-CMP REMOVAL OF SURFACE

CONTAMINATS FROM SILICON WAFER

## AMENDMENT AFTER FINAL

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

The Office Action mailed December 5<sup>th</sup>, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.